

Abstract

An automated semiconductor parametric test system has a control module that is operable to concurrently control both operation of semiconductor test equipment and operation of parametric test instrumentation. A state oscillator module is controlled by the control module, and further may be operated by the control module in some embodiments to control the state of other system modules in synchronization with other system events. A parametric test equipment module facilitates control of the semiconductor parametric test equipment, and a test instrumentation module facilitates control of the parametric test instrumentation.

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